## 3D OPILCS

LTPRSM Series are LED Pattern Projectors specifically designed for the most demanding 3D profiling and measurement applications. Triangulation techniques require that structured light be directed onto a sample at a considerable angle from vertical. Tilting the light source pattern becomes essential to ensure that patterned light is properly and homogeneously focused across the entire sample surface. LTPRSM pattern projectors integrate a precision tilting mechanism based on the Scheimpflug criterion. This also ensures that the focus doesn't change when the pattern is tilted. Moreover, the internal focus mechanism offers the maximum optical throughput. The projected light path is effectively coupled to the pupil aperture of any --mount lens.

## Examples of 3D measurement set-ups:

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## LTPRSM SERIES

## 3D LED Pattern Projectors with tilt and focus adjustment



LTPRSM pattern projector with a
standard C-mount lens
LTPRSM pattern proiector with a
standard Cmount lens

Bi-Telecentric lenses used for both projection and vision
$90^{\circ}$ configuration with zero distortion macro lenses



## KEY ADVANTAGES

(1) Scheimpflug tilt adjustment for homogeneous focusing of the pattern features

2 Tilt adjustment compatible with C-mount optics focus is maintained even when the pattern is tilted
(3) Light Condenser focusing mechanism
for excellent optical coupling and light throughput


Enhanced optical power
due to the high numerical aperture condenser lens


Without tilt adjustment, the pattern features are only partly focused


With the Scheimpflug adiustment, focus is retained across the entire plane

## LTPRSM SERIES

## 3D OPIICS





|  | optical properties |  | device power rafings |  |  | led power ratings |  |  |
| :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: |
| part number | light color, peak wovelength | output flux (lumen) | minimum <br> DC voltage <br> (volt) | maximum <br> DC voltage <br> (volt) | power consumption (watt) | forward <br> voltage <br> (volt) | forward current (mA) | pulse rating @ 0,1duty/kHzz (mA) |
| LTPRSM3W/R | red, 630 nm | $>11$ | 12,0 | 24,0 | <2 | 2,3 | 350,0 | < 1800 |
| LTPRSM3W/G | green, 520 nm | $>19$ | 12,0 | 24,0 | <2 | 3,5 | 350,0 | <1800 |
| LTPRSM3W/B | blue, 460 nm | $>4,5$ | 12,0 | 24,0 | <2 | 3,5 | 350,0 | <1800 |
| LTPRSM3W/W | white | >21 | 12,0 | 24,0 | <2 | 3,5 | 350,0 | <1800 |

The pattern tilt control is easily tuned by means of a click-stop knob with $2.5^{\circ}$ sensitivity to precisely meet the Scheimpflug condition. The optimum coupling with any C-mount lens is obtained with the internal focus mechanism. The LED source is imaged into the lens aperture to achieve maximum optical throughput.

LTPRSM projectors are compatible with any $2 / 3^{\prime \prime}$ (-mount lens; the lens is simply screwed into the device just like with a -mount camera. A simple mechanical mount specifically designed to clamp LTPRSM projectors is included into the product package.

Built-in switching electronics controls and stabilizes the amount of current in the device. The brightness level can be easily tuned by means of a trimmer. Moreover, the inner circuitry can be bypassed in order to directly drive the LED: just wire the black and blue cables to the power supply instead of the black and brown ones and make sure that the maximum rates are not exceeded.

## 3D OPTICS

The projection pattern inside the unit can be changed and integrated with ease: just remove the C-mount adaptor by loosening the set-screws and fix the pattern by screwing the retaining ring.
Different types of stripe and grid patterns are available; the chart below shows the line thickness $(0,05 \mathrm{~mm})$ and the gap between neighboring lines for each pattern type.
When these features are projected, they become $1 / M$ times larger, with " $M$ " being the magnification of the projection lens.
The number of lines mentioned after each part number indicates the number of features on the active area of the pattern.

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## LTPRSM SERIES

## Pattern selection



STRIPE PATTERNS
PT 00000300 P: 8 lines in projection area


PTST 050450 P: 16 lines in projection area PRGR 050450 P: $16 \times 16$ lines in projection area


PTST 050100 P : 53 lines in projection area PTGR050 100 P: $53 \times 53$ lines in projection orea


## 3D OPIICS

## Projection lens selection



LTPRSM units can be interfaced with any type of optics, but the best results are achieved with bitelecentric lenses.
The projection area is undistorted since filing the pattern only causes a linear extension along one direction.
Very good results can also be obtained with zero distortion macro lenses; here, the magnification changes along both axes, but image resolution and distortion are such that 3 D reconstruction can still be easily performed.
With non biteleceentric lenses, a square pattern becomes a trapezoid in the projection plane, whose parallel sides are indicated as "w" and "W" in the "MACRO" chart below.
The projection data shown in the chart are also a good approximation for standard C-mount lenses used in macro mode (eventually equipped with spacers).


## Projection Area with MACRO (MC3-03x and MC Series) and standard lenses

|  |  | $=90^{\circ}$ |  |  | $\vartheta^{\prime}=15^{\circ}$ |  |  | $9^{\prime}=30^{\circ}$ |  |  |  | $\vartheta^{\prime}=45^{\circ}$ |  |  |  |
| :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: |
|  | projection distance (mm) | $\begin{aligned} & \text { projection } \\ & \text { w (W), } \\ & \\ & \\ & \text { (mm } \end{aligned}$ | $\begin{array}{ll} \text { area } \\ x & H \\ x & \mathrm{~mm}) \end{array}$ | $\begin{gathered} \text { pottern tilf } \\ 9^{\prime} \end{gathered}$ | $\begin{aligned} & \text { projection } \\ & \text { w } \quad(\text { W) } \\ & \\ & \\ & (\mathrm{mm} \end{aligned}$ | area <br> $x$ H <br> x mm) | $\begin{gathered} \text { pattern tilt } \\ 9^{\prime} \end{gathered}$ | w | projection <br> (W) <br> (mm | $\begin{array}{ll} \text { n orea } \\ x & H \\ x & \text { Hm) } \end{array}$ | $\begin{gathered} \text { pattern tilt } \\ \vartheta^{\prime} \end{gathered}$ | w | projection <br> (W) <br> (mm | area <br> $x \quad H$ <br> $x \mathrm{~mm}$ ) | pattern tilt 9' |
| 1 x | 46,0 | $8,0 \quad(8,0)$ | x 8,0 | $0^{\circ}$ | 7,7 (8,3) | x 8,0 | $15,0^{\circ}$ | 7,5 | $(8,6)$ | $\times 8,1$ | $30,0^{\circ}$ | 7,3 | $(8,9)$ | x 8,1 | $45,0^{\circ}$ |
| 0,75 X | 48,0 | 10,7 (10,7) | 10,7 | $0^{\circ}$ | 10,3 (11,1) | 10,9 | $11,4^{\circ}$ | 10,0 | $(17,6)$ | x 11,4 | 23,5 ${ }^{\circ}$ | 9,6 | (12,1) | x 12,3 | $37,0^{\circ}$ |
| 0,5 X | 60,0 | 16,1 (16,1) | x 16,1 | $0^{\circ}$ | 15,5 (16,7) | x 16,5 | 7,60 |  | $(17,5)$ | - 17,9 | $16,2^{\circ}$ | 14,3 | $(18,4)$ | x 20,7 | $26,7^{\circ}$ |
| 0,33 X | 92,0 | 24,3 (24,3) | x 24,3 | $0^{\circ}$ | 23,4 (25,3) | x 25,1 | $5,{ }^{\circ}$ | 22,5 | $(26,5)$ | x 27,8 | 10,8 ${ }^{\circ}$ | 21,4 | $(28,1)$ | + 33,3 | $18,3^{\circ}$ |
| 0,2 X | 136,0 | $40,1(40,1)$ | x 40,1 | $0^{\circ}$ | 38,6 (41,6) | x 42,1 | $3,1{ }^{\circ}$ | 37,0 | $(43,6)$ | x 46,2 | 6,6 ${ }^{\circ}$ | 35,1 | $(46,6)$ | x 56,8 | $11,4^{\circ}$ |
| 0,1 X | 275,0 | 79,5 (79,5) | - 79,5 | $0^{\circ}$ | $76,6 \quad(82,6)$ | x 82,4 | 1,60 | 73,5 | $(86,6)$ | x 92,3 | 3,4 ${ }^{\circ}$ | 69,6 | $(92,6)$ | + 114,2 | 5, $8^{\circ}$ |



